

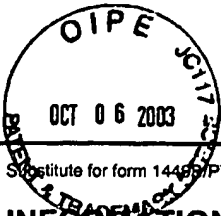
PTO/SB/08A (08-03)

Substitute for form 1449A/PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		<b>Complete if Known</b>	
		Application Number	10/632,662
		Filing Date	August 1, 2003
		First Named Inventor	Staple, Bevan
		Art Unit	
		Examiner Name	
Sheet	1	of	3
		Attorney Docket Number	019930-003110US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number Number Kind Code <sup>2</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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Examiner Signature	<i>Michelle R. Connelly-Cushwa</i>	Date Considered	3/4/04
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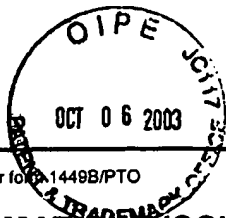
Substitute for form 1449 PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (use as many sheets as necessary)		<b>Complete if Known</b>	
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Sheet	2	of	3
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NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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Examiner Signature	<i>Michael R. Connolly/Cutler</i>	Date Considered	3/4/04
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PTO/SB/08B (08-03)

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Examiner Signature	<i>Michelle R Connolly</i>	Date Considered	3/4/04
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